

Please provide the following new abstract of the disclosure:

A method evaluating a measuring electron microscope, comprising the steps of setting such modes of operation of a microscope, that will be used for subsequent measurements of sizes and line edge roughness; introducing a test-object which has a known straight edge into a chamber of objects of the microscope; orienting the test object on a stage of the microscope; scanning the test object with an electron beam; obtaining an image of the edge of the test object and saving the image in a digital form; localizing the edge of the test object and saving the image in a digital form; localizing the edge of the test object on the image on each line of scanning; producing storing a set of values of a coordinate $X(i)$ which correspond to a position of the edge of an i -th line of scanning; approximating the sets of values $X(i)$ with a straight line; calculating deviations $P(l)$ of coordinates $X(i)$ from a straight line on each line of scanning; analyzing a set of values of the deviations $\Delta(i)$; calculating an Δ_{ave} and a maximal deviation Δ_{max} and if a maximum value of deviation Δ_{max} exceeds an acceptable tolerance of measurement, making a conclusion whether or not the microscope can be used for measurements and whether or not an adjustment is needed.